

ABSTRACT OF THE DISCLOSURE

An alignment measuring system includes a focusing diode, a light source, an image sensor, first and second splitters, a focusing diode, and a controller. The first splitter directs a portion of light from the light source toward a wafer, and directs light returned by the wafer to the second splitter. The second splitter directs a first portion of the light toward the image sensor, and a second portion of the light toward the focusing diode, and control the ratio of the first and second portions in response to a control signal from the controller. The image sensor receives the first portion of light and produces a detection signal. The controller receives the detection signal, determines an alignment state of the wafer, and controls a stage to align and position the wafer.